

# Advancements in X-ray Wavefront Sensing and At-wavelength Metrology at the Advanced Photon Source



Xianbo Shi, Zhi Qiao, Luca Rebuffi, Matthew Highland, Matthew Frith, and Lahsen Assoufid

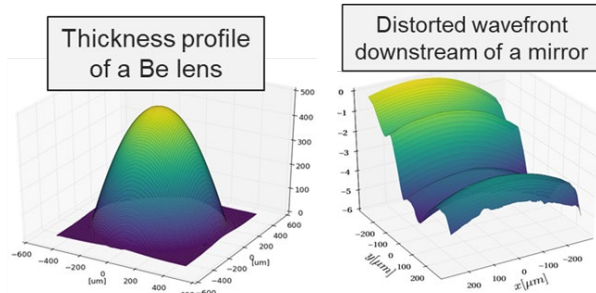
*Advanced Photon Source, Argonne National Laboratory, Lemont, IL 60439, USA*

**PhotonMEADOW23**

Sep. 12-14, 2023

# WAVEFRONT SENSING TECHNIQUES

## Beamline X-ray optics characterization and diagnostics at the APS



### X-ray wavefront sensing tools

- Grating interferometry
- Speckle tracking
- Coded-mask-based technique

Apply

### Optics/beam characterization

- At-wavelength metrology
- Wavefront sensing
- Coherence measurements

Support Extend

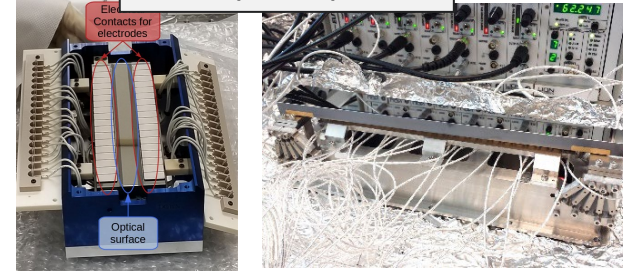
### Optics development

- Wavefront-preserving optics
- Adaptive optics
- Phase corrector

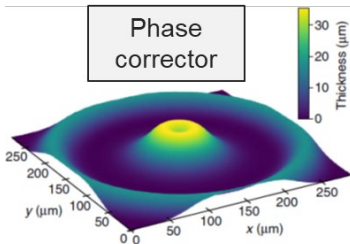
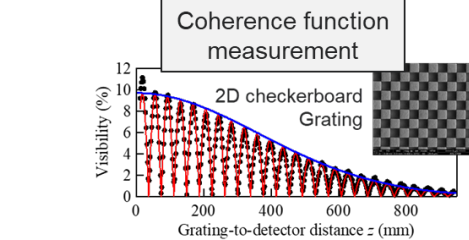
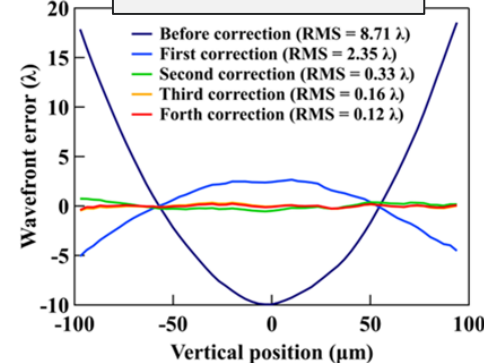
### Beamline diagnostic

- Wavefront and coherence monitor
- Beamline control and optimization

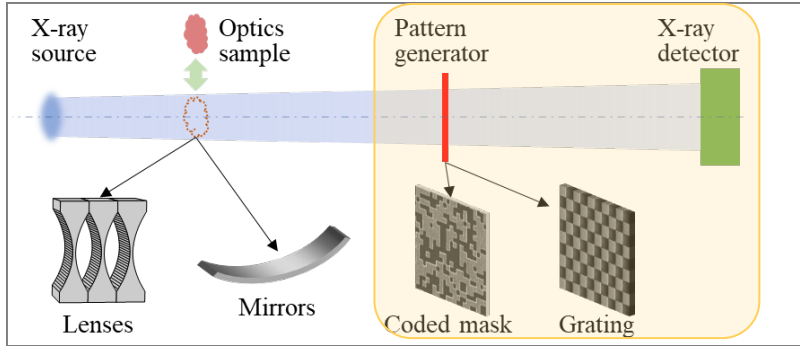
### Adaptive optics



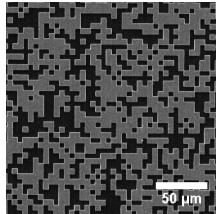
### Wavefront correction



# WAVEFRONT SENSING TECHNIQUES



## Coded-mask-based Wavefront Sensor

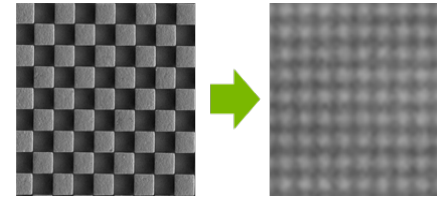


- Designed non-periodic pattern
- Ultra-high-contrast >30%
- Pre-knowledge of the pattern
- High spatial resolution
- High phase sensitivity
- Better noise robustness
- Flexible and easy to use

X. Shi, et al., US patent US20220265231 (2022).  
 Z. Qiao, et al., Appl. Phys Lett. 119, 011105 (2021).  
 Z. Qiao, et al., *Optica* 9, 391 (2022).  
 Z. Qiao, et al., Opt. Express 28, 33053 (2020).  
 Z. Qiao, et al., Proc. SPIE 11492, 114920O (2020).  
 Z. Qiao, et al., J. Imaging 7, 249 (2021).  
 X. Shi, et. al, Proc. SPIE 12240, 122400H (2022).

## Grating interferometry

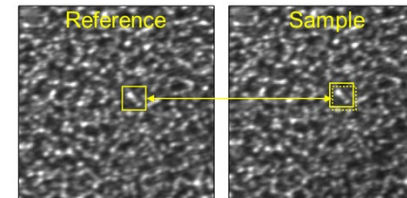
- Phase or absorption gratings with periodic pattern
- Fourier-based analysis for grating pattern shifts



Harold H. Wen et al. Opt Lett. 35, 1932 (2010)  
 W. Grizolli, et al. Proc. SPIE 10385, 1038502 (2017)  
 W. Grizolli, et al., AIP Conference Proceedings, 2054, 060017 (2019)

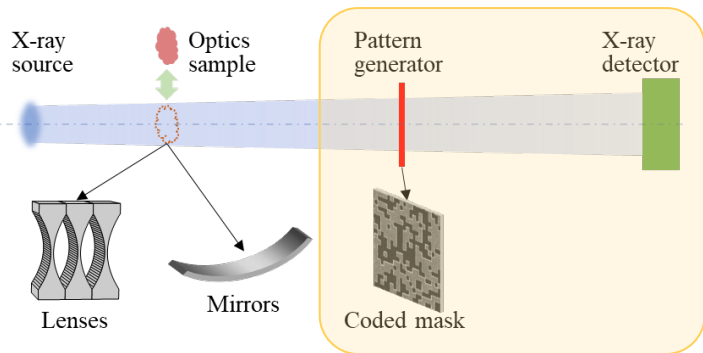
## Speckle tracking

- Speckle generator (sandpaper, membrane filters) with completely random pattern
- Based on near-field speckle pattern shifting



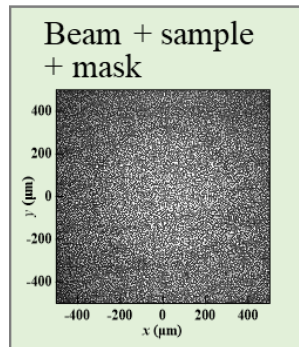
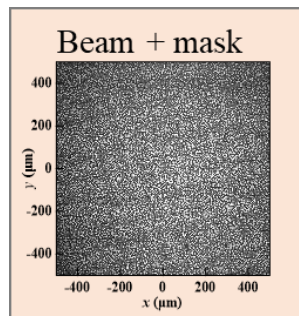
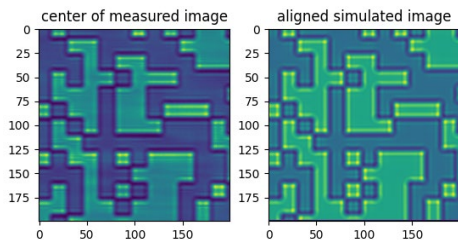
S. Berujon et al., J Synchrotron Radiat, 27, 284 (2020)  
 S. Berujon et al., J Synchrotron Radiat, 27, 293 (2020)

# CODED-MASK-BASED WAVEFRONT SENSOR DESIGN



## Two operation modes

- Relative metrology/imaging mode (two measured images)
- Absolute wavefront sensing mode (simulated reference images)



## Data analysis

Absolute wavefront sensing mode ① ②

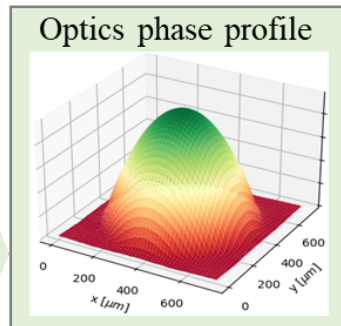
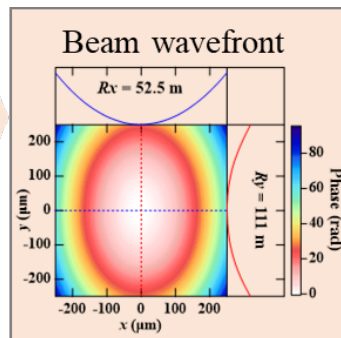
① Wavelet-transform-based speckle tracking

② Machine-learning-based: SPINNet

③ Correlation-based speckle tracking

④ Maximum-likelihood optimization

Relative metrology/imaging mode ① ② ③ ④

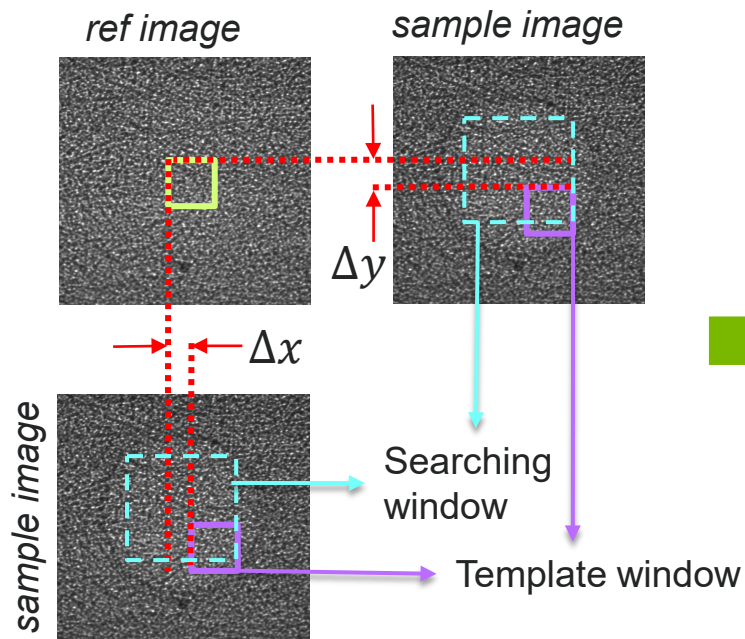


# CODED-MASK-BASED WAVEFRONT SENSING

## Single-shot measurements

- Data analysis methods:

- Correlation-based speckle tracking



Pixel-by-pixel analysis

Find  $\Delta x$  and  $\Delta y$  to maximize  $c(x, y)$

$c(x, y) = \text{cross-correlation}(\text{template window}, \text{searching window})$

# CODED-MASK-BASED WAVEFRONT SENSING

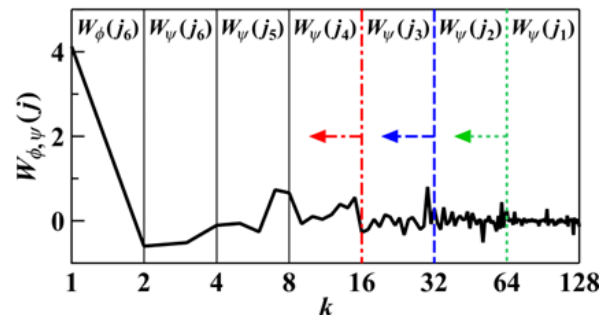
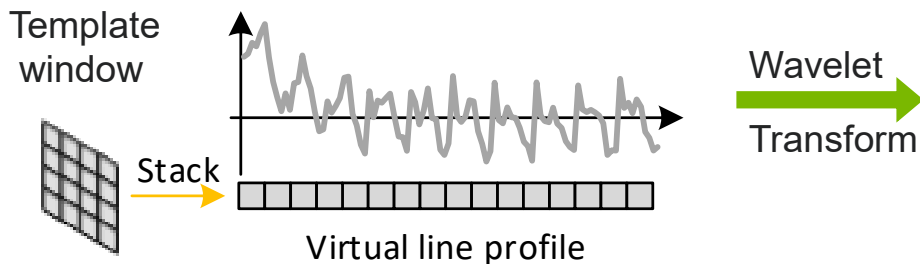
## Single-shot measurements

### ▪ Data analysis methods:

- Correlation-based speckle tracking
- **Wavelet-transform-based speckle tracking**

Z. Qiao, et al., Proc. SPIE 11492, 114920O (2020).

$$I^{s/r}(t) = \frac{1}{\sqrt{n}} \sum_k W_\phi^{s/r}(j_m, k) \phi_{j_m, k}(t) + \frac{1}{\sqrt{n}} \sum_{j=j_1}^{j_m} \sum_k W_\psi^{s/r}(j, k) \psi_{j, k}(t)$$



Find  $\Delta x$  and  $\Delta y$  to minimize  
Euclidean distance square

$$r = \sum |W_{\phi, s} - W_{\phi, r}|^2$$

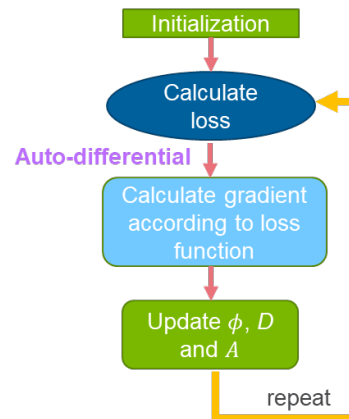
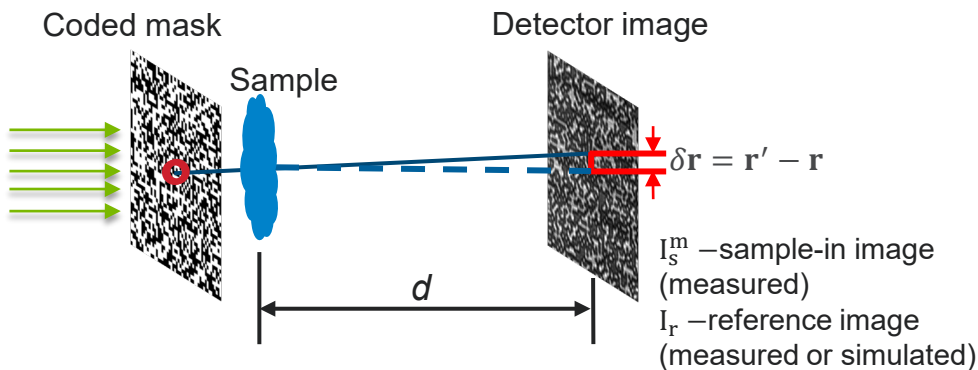


# CODED-MASK-BASED WAVEFRONT SENSING

## Single-shot measurements

### ▪ Data analysis methods:

- Correlation-based speckle tracking
- Wavelet-transform-based speckle tracking
  - Z. Qiao, et al., Proc. SPIE 11492, 114920O (2020).
- **Maximum-likelihood optimization**
  - Z. Qiao, et al., Appl. Phys Lett. 119, 011105 (2021).



$$I_s(\mathbf{r}') = \frac{A(\mathbf{r})}{C(\mathbf{r})} \{ \bar{I}_r(\mathbf{r}) + D(\mathbf{r}) [I_r(\mathbf{r}) - \bar{I}_r(\mathbf{r})] \}$$

### Loss function minimization

$$\sum [I_s - I_s^m \log(I_s)] + \alpha TV(\|D\|_2) + \alpha TV(\|A\|_2) + \beta TV(\|\phi\|_2)$$

$TV$  – total variation

Pixel wise  optimization

**Sample**  
Absorption:  $A$   
Phase:  $\phi$   
Dark-field:  $D$

# CODED-MASK-BASED WAVEFRONT SENSING

## Single-shot measurements

### ▪ Data analysis methods:

- Correlation-based speckle tracking
  - Wavelet-transform-based speckle tracking
- Z. Qiao, et al., Proc. SPIE 11492, 114920O (2020).

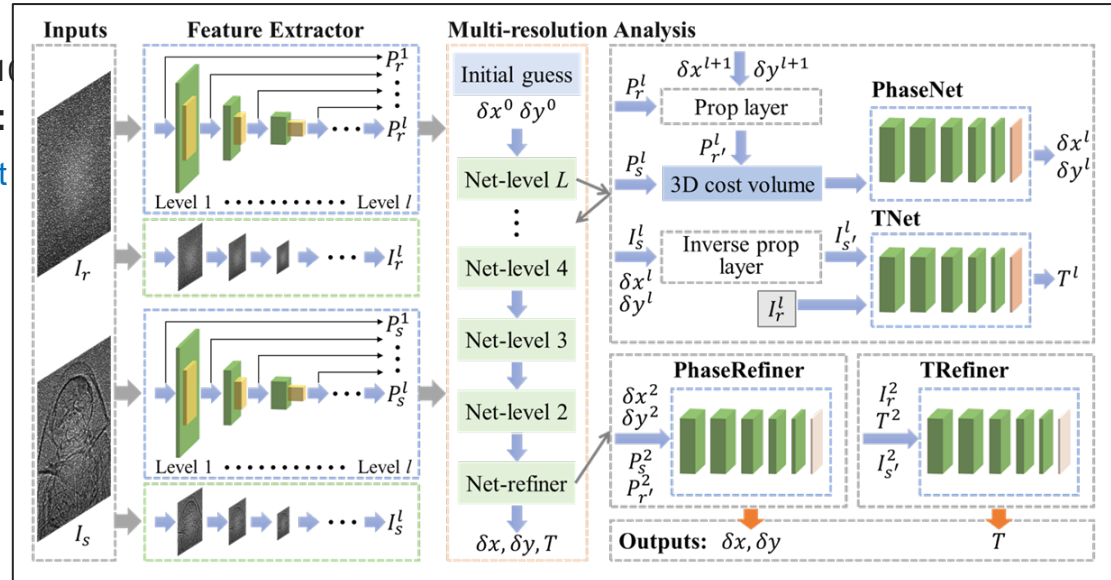
- Maximum-likelihood optimization

Z. Qiao, et al., Appl. Phys Lett. 119, 011101 (2021).

- **Machine-learning-based method:**

**SPINNet (Speckle-based Phase-contrast Imaging Neural Network)**

Z. Qiao, et al., Optica 9, 391 (2022).



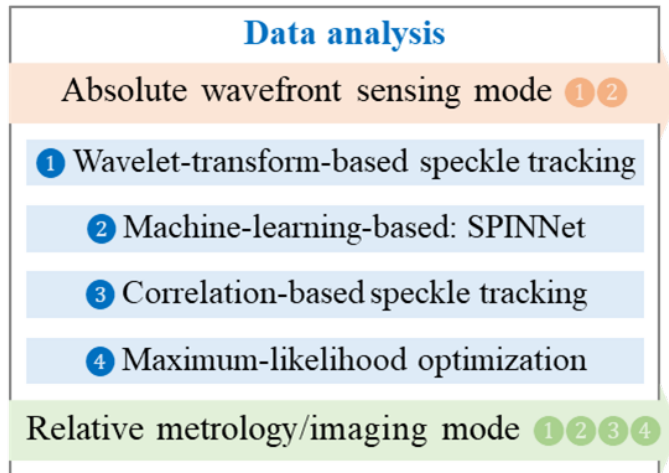


# CODED-MASK-BASED WAVEFRONT SENSING

## Single-shot measurements

### ▪ Data analysis methods:

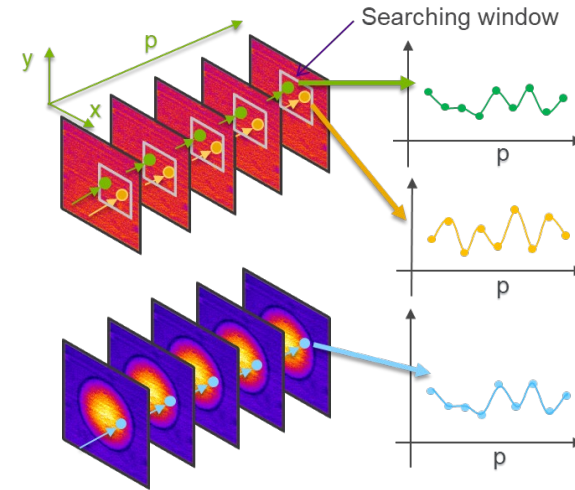
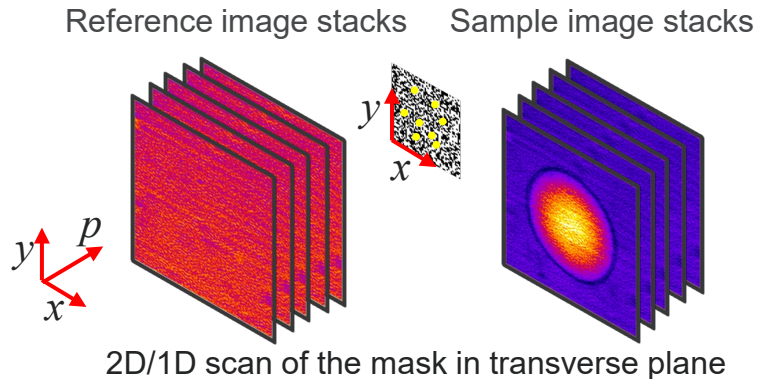
- Correlation-based speckle tracking
- Wavelet-transform-based speckle tracking  
Z. Qiao, et al., Proc. SPIE 11492, 114920O (2020).
- Maximum-likelihood optimization  
Z. Qiao, et al., Appl. Phys Lett. 119, 011105 (2021).
- **Machine-learning-based method:**  
SPINNet (Speckle-based Phase-contrast Imaging Neural Network)  
Z. Qiao, et al., Optica 9, 391 (2022).



# CODED-MASK-BASED WAVEFRONT SENSING

## Scanning mode measurements for improved resolution and sensitivity

### ▪ Relative metrology/imaging mode



### ▪ Data analysis methods:

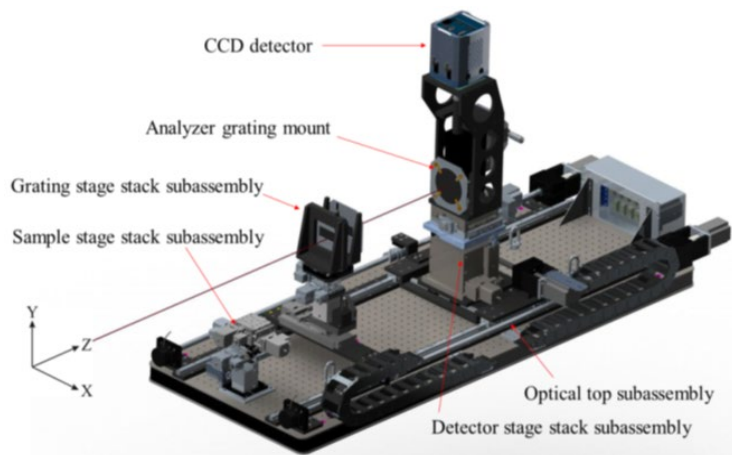
- Correlation-based speckle **vector** tracking
- Wavelet-transform-based speckle **vector** tracking  
Z. Qiao, et al., *Opt. Express* 28, 33053 (2020).
- Maximum-likelihood optimization  
Z. Qiao, et al., *J. Imaging* 7, 249 (2021).

Maximize 1D cross-correlation

Minimize Euclidean distance square of Wavelet coefficients

Minimize loss function summing over all images

# WAVEFRONT SENSING INSTRUMENTS



L. Assoufid et al., Rev. Sci. Instrum. 87, 052004 (2016).

Portable WF sensor

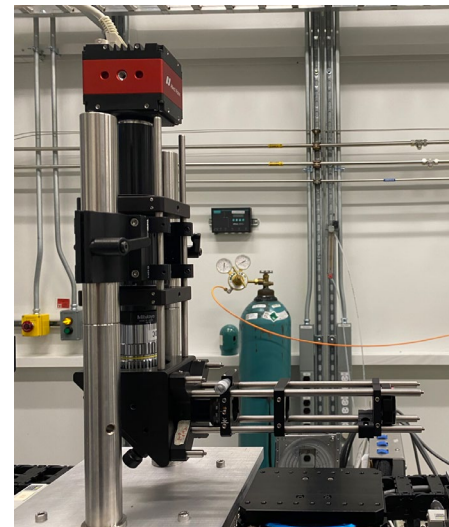
## APS beamlines

- X-ray optics and detector testing beamline (1-BM)
- Instrumentation Development, Evaluation, & Analysis (IDEA) beamline (28-ID-B) (Oct. 2021 — Apr. 2023)



Zoomable WF sensor

M. Frith, et al., Rev. Sci. Instrum. (2023) submitted.



Compact WF sensor

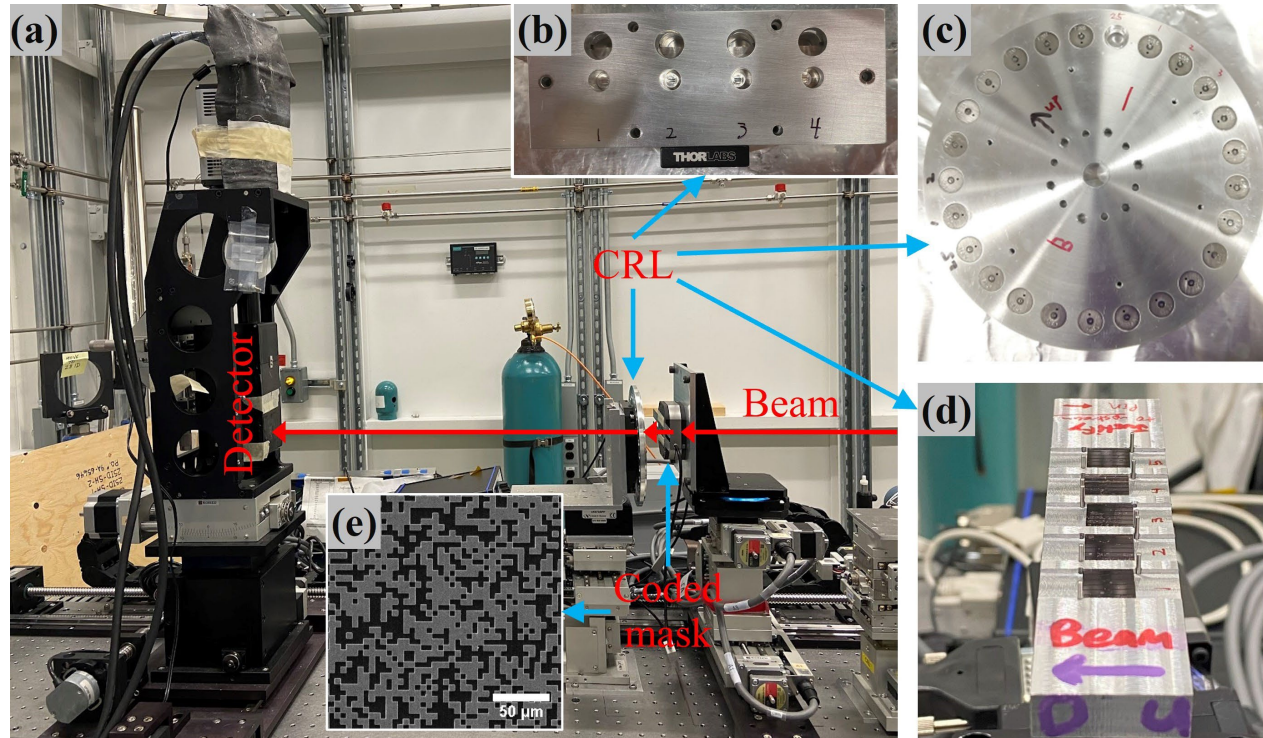
A standard diagnostic tool optimized for each APS-U beamline.

# AT-WAVELENGTH METROLOGY APPLICATION



# AT-WAVELENGTH METROLOGY APPLICATION

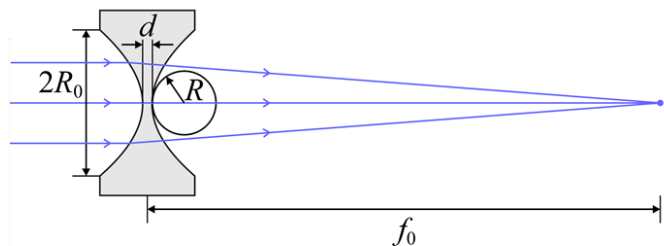
## CRL measurements at APS 28-ID-B and 1-BM beamline



- APS and APS-U beamlines:  
>600 Be lenses, >100 Al and diamond lenses
- Other facilities:  
Australian Synchrotron:  
159 Al and Be lenses
- Many R&D lenses from  
ESRF, Euclid, JJ X-ray,  
Materion, KIT, RXoptics,  
PALM-scientific, APS-  
LDRDs

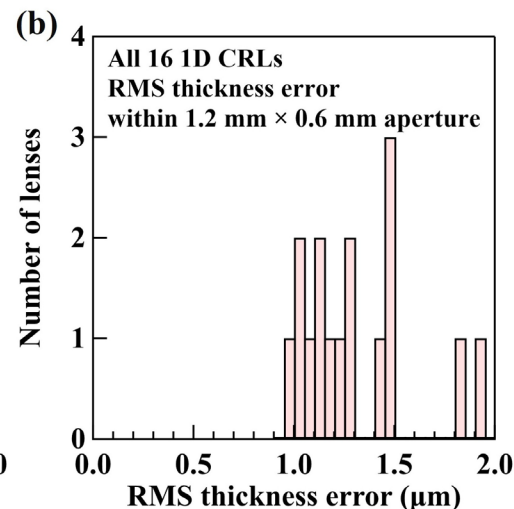
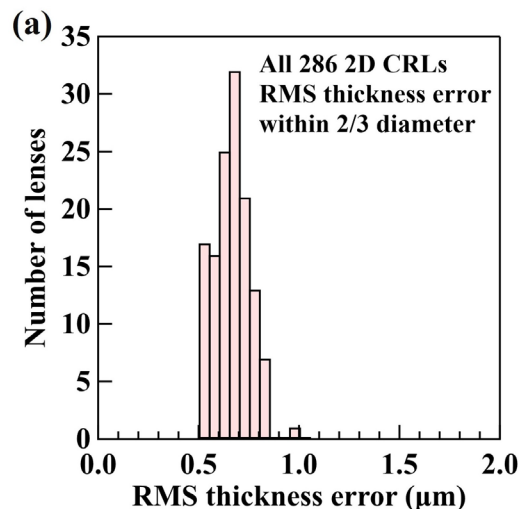
# AT-WAVELENGTH METROLOGY APPLICATION

## CRL measurements at APS 28-ID-B and 1-BM beamline



- **Radius of curvature  $R$ :** radius values standard deviation  $<1\%$ , all within  $\pm 2.5\%$  of the mean value
- **Thickness error:** RMS thickness error after removing best-fit parabola over the central two-third of the lens diameter  $< 1.0 \mu\text{m}$
- **Defects and cracks:**  $<5\%$  lenses were detected with defects  $>10 \mu\text{m}$  PV thickness error, replacement lenses within specs.

### Statistics of all APS-U Be lenses (after replacements)



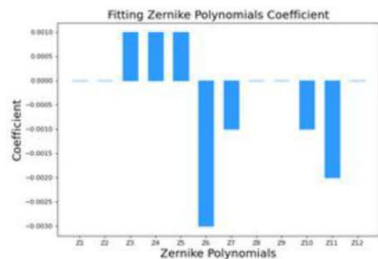
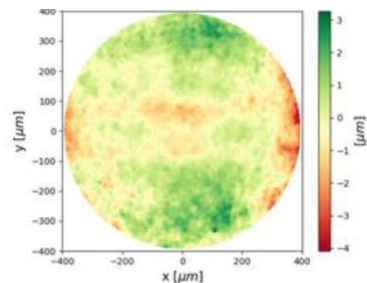


# AT-WAVELENGTH METROLOGY APPLICATION

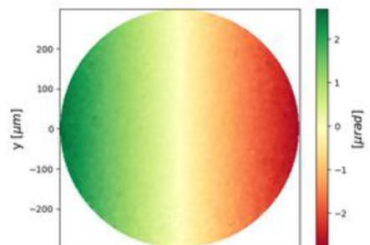
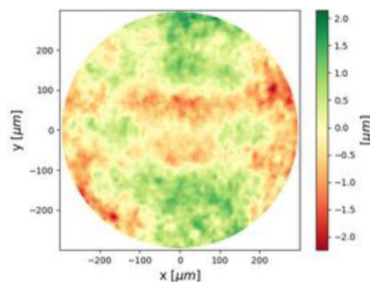
## CRL measurements at APS 28-ID-B and 1-BM beamline

### Example **good** lens

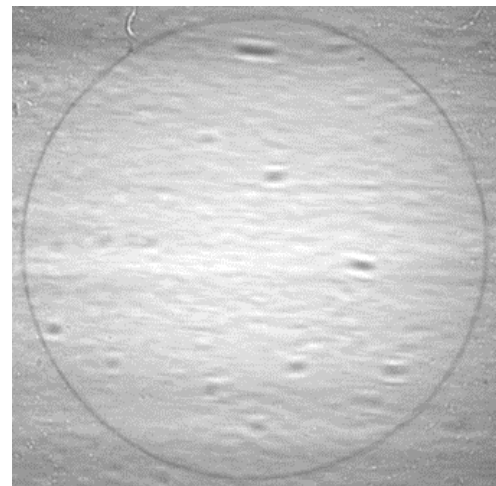
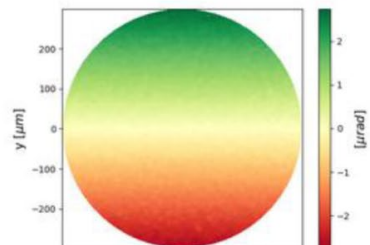
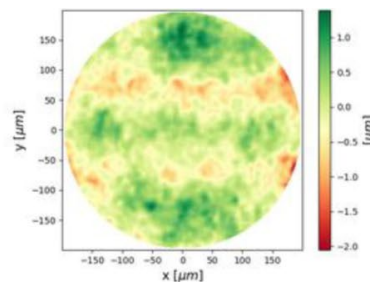
Radius: 193.3  $\mu\text{m}$ ;  
800  $\mu\text{m}$  fitting diameter  
RMS: 0.99  $\mu\text{m}$   
PV: 7.17  $\mu\text{m}$



**600  $\mu\text{m}$  fitting diameter**  
**RMS: 0.64  $\mu\text{m}$**   
**PV: 4.36  $\mu\text{m}$**



**400  $\mu\text{m}$  fitting diameter**  
**RMS: 0.41  $\mu\text{m}$**   
**PV: 2.84  $\mu\text{m}$**

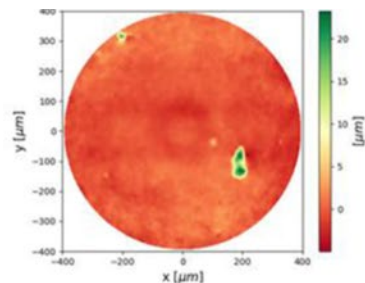


# AT-WAVELENGTH METROLOGY APPLICATION

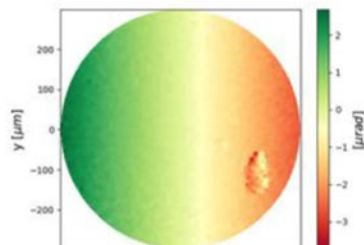
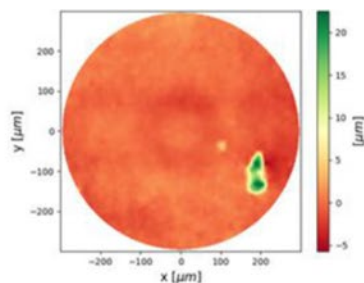
## CRL measurements at APS 28-ID-B and 1-BM beamline

### Example **rejected** lens

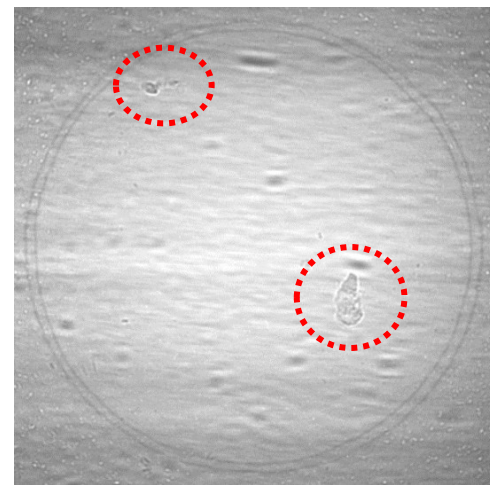
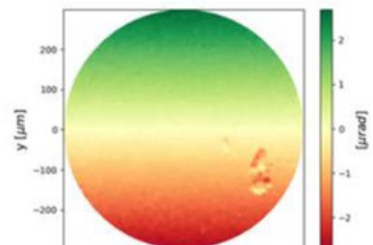
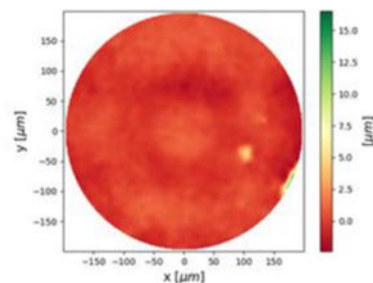
Radius: 196.9  $\mu\text{m}$ ;  
800  $\mu\text{m}$  fitting diameter  
RMS: 1.70  $\mu\text{m}$   
PV: 28.15  $\mu\text{m}$



**600  $\mu\text{m}$  fitting diameter**  
**RMS: 1.88  $\mu\text{m}$**   
**PV: 28.04  $\mu\text{m}$**



400  $\mu\text{m}$  fitting diameter  
RMS: 0.79  $\mu\text{m}$   
PV: 18.49  $\mu\text{m}$



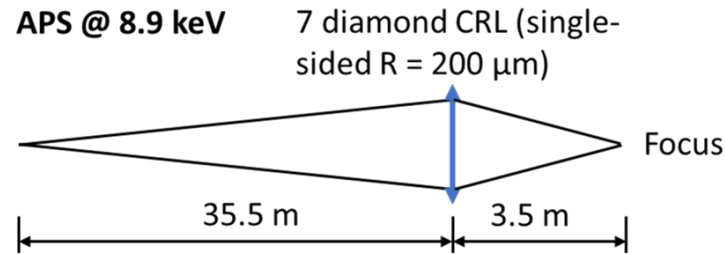
# AT-WAVELENGTH METROLOGY APPLICATION

## CRL thickness error database

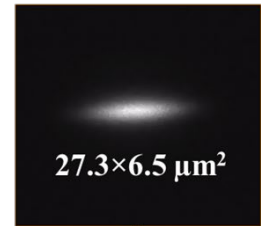
### Transfocator arrangement

| Cassette         | 1    | 2   | 3    | 4    | 5    | 6    | 7    | 8    |
|------------------|------|-----|------|------|------|------|------|------|
| Type             | 2D   | 2D  | 2D   | 2D   | 2D   | 2D   | 2D   | 2D   |
| N                | 1    | 1   | 1    | 2    | 4    | 8    | 8    | 16   |
| R, $\mu\text{m}$ | 1000 | 500 | 200  | 200  | 200  | 200  | 100  | 100  |
|                  | H74  | F1  | T296 | D104 | C135 | C138 | D180 | D290 |
|                  |      |     |      | D137 | C137 | C142 | D183 | D292 |
|                  |      |     |      |      | C149 | C143 | D185 | D293 |
|                  |      |     |      |      | D126 | C147 | D189 | D296 |
|                  |      |     |      |      |      | C151 | D193 | D297 |
|                  |      |     |      |      |      | C154 | D195 | D301 |
|                  |      |     |      |      |      | D101 | D199 | D305 |
|                  |      |     |      |      |      | D102 | D205 | D306 |
|                  |      |     |      |      |      |      |      | D307 |
|                  |      |     |      |      |      |      |      | D309 |
|                  |      |     |      |      |      |      |      | D681 |
|                  |      |     |      |      |      |      |      | D682 |
|                  |      |     |      |      |      |      |      | D685 |
|                  |      |     |      |      |      |      |      | D686 |
|                  |      |     |      |      |      |      |      | D687 |
|                  |      |     |      |      |      |      |      | D688 |

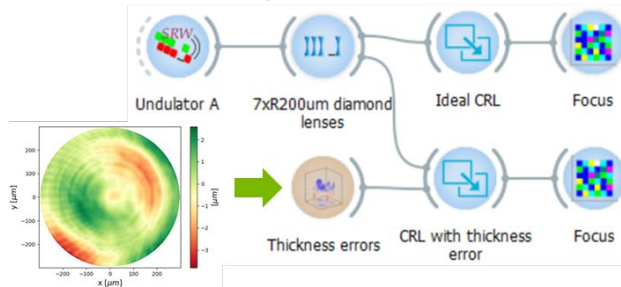
### Performance simulation and beamline design



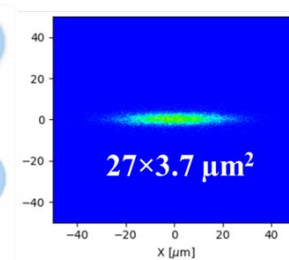
Measured focus



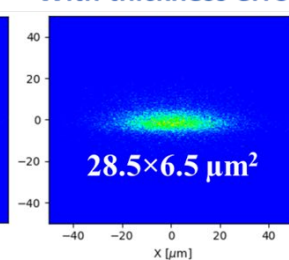
Oasys-Shadow simulation



Ideal lens

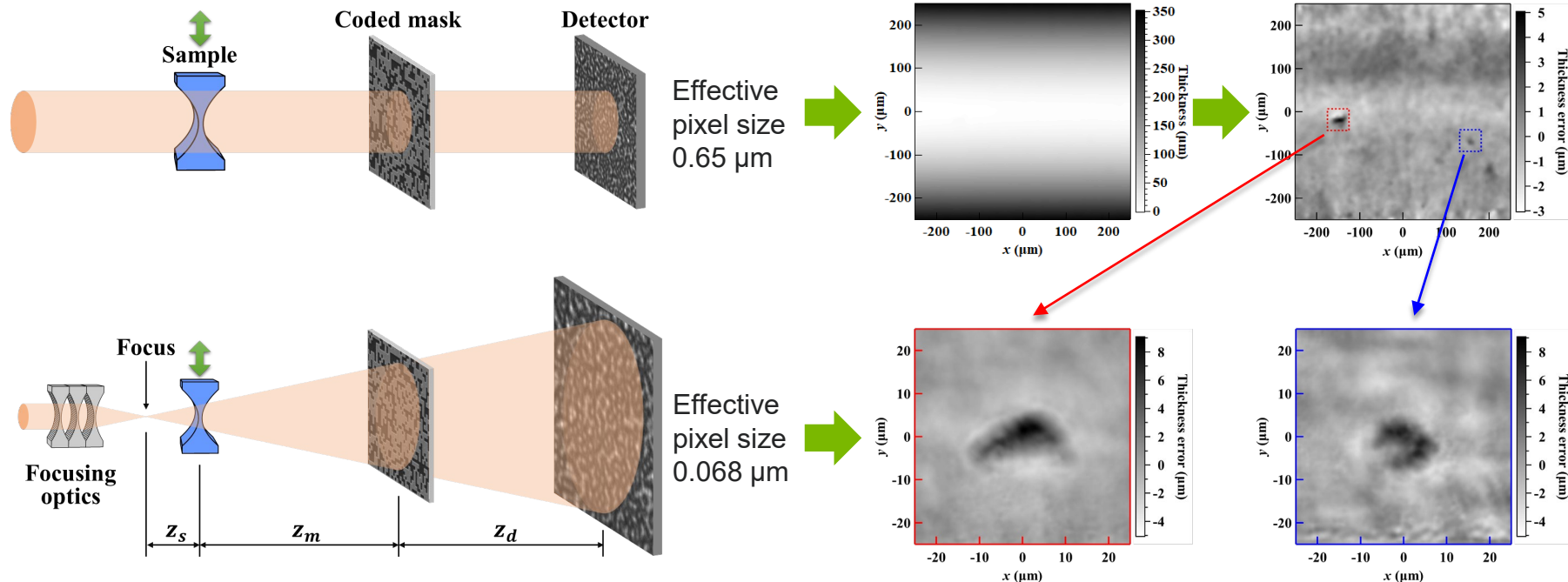


With thickness error



# AT-WAVELENGTH METROLOGY APPLICATION

## Variable-resolution metrology of CRL



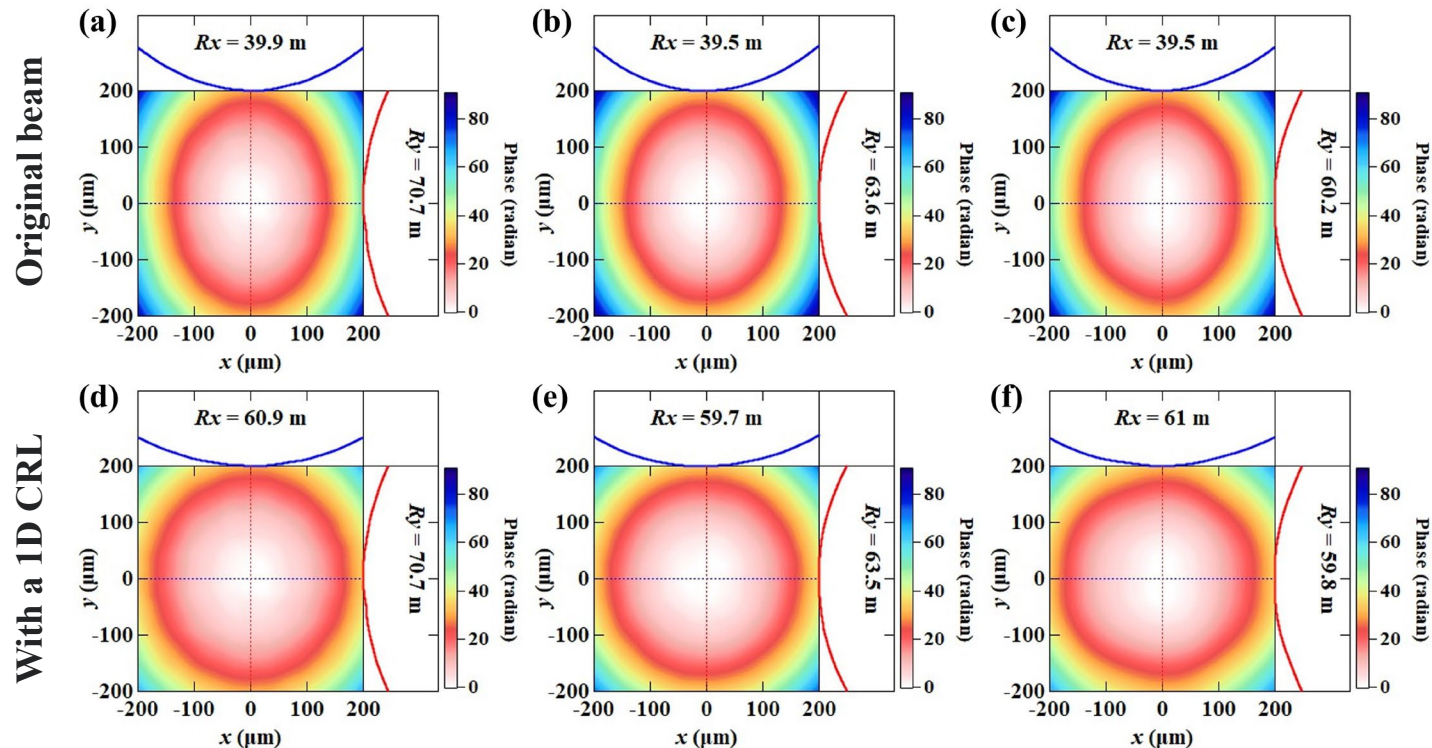
$$\text{Magnification: } \frac{z_s + z_m + z_d}{z_s} = 9.5$$

# WAVEFRONT SENSING APPLICATIONS



# WF SENSOR PROTOTYPE TESTING

## Absolute wavefront measurements at APS 28-ID-B



# WAVEFRONT SENSING APPLICATION

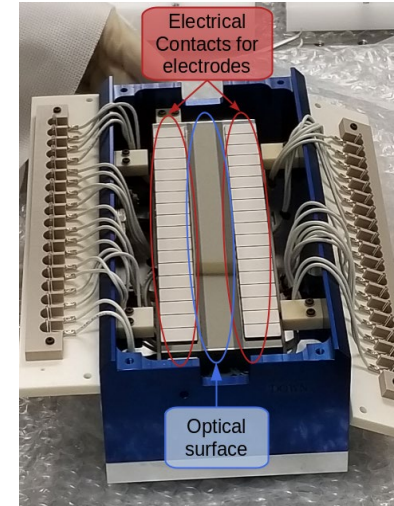
## Adaptive mirrors: dynamic focusing and wavefront shaping

APS mechanical bender mirrors



J. Anton, et al., Proc. SPIE 11100, 111000B (2019).

JTEC bimorph mirrors



X. Shi, et al., Proc. SPIE 11491, 1149110 (2020).

# WAVEFRONT SENSING APPLICATION

## Advanced beamline optics automatic control system

- Real-time machine-learning-driven control system of a deformable mirror for achieving aberration-free X-ray wavefronts

L. Rebuffi, et al., Opt. Express **31**(13), 21264 (2023).

- AutoFocus: AI-driven alignment of nanofocusing X-ray mirror systems

L. Rebuffi, et al., Opt. Express (2023) submitted.

Optica Open. Preprint. doi: 10.1364/opticaopen.23934903.v3

An optics automation system combining adaptive optics, wavefront sensing, and ML/AI control algorithm for beamline auto-alignment/focusing and wavefront control.

12:30 – 13.00 AI-driven real-time optics control system to achieve aberration-free coherent wavefronts at 4th-generation synchrotron radiation and free electron laser beamlines  
Luca Rebuffi

# SUMMARY

- The APS established a full bank of techniques and tools for advanced X-ray metrology and wavefront sensing
- Evaluated quality and performance of various optical components at the IDEA Beamline and 1-BM beamline
- Complete design and fabrication of dedicated WF sensors for the commission and operation of APS-U beamlines
- Future work:
  - WF sensing technique
    - Develop calibration procedure and analysis for nanofocusing beam WF sensing
    - Improve SPINNet (training with targeted beamline conditions)
    - User friendly data collection and analysis code development
  - Continue developing ML-based control and AI-based auto-alignment system

# ACKNOWLEDGEMENT

Zhi Qiao (ShanghaiTech Uni.)

Matthew Highland

Matthew Frith

Luca Rebuffi

Michael Wojcik

Lahsen Assoufid

Yudong Yao

Mathew Cherukara

Kazuto Yamauchi (OSAKA Uni.)

Takato Inoue (Nagoya Uni.)

Yoshio Ichii (JTEC Corporation)

Gautam Gunjala (UC Berkeley & ALS-LBNL)

Antoine Wojdyla (ALS-LBNL)

Kenneth Goldberg (ALS-LBNL)

Laura Waller (UC Berkeley)

This work was supported by the US Department of Energy, Office of Science, Office of Basic Energy Sciences, under Contract No. DE-AC02-06CH11357.

# THANK YOU!